



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Chen et al.

Serial No.: 10/033,732

Filed: December 27, 2001

Confirmation No. Unknown

For: Conductive Polishing Article  
For Electrochemical Mechanical  
Polishing

Group Art Unit: Unknown

Examiner: Unknown

Assistant Commissioner for Patents  
Washington, D.C. 20231

CERTIFICATE OF MAILING  
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Date

Keith R. [Signature]  
Signature

Dear Sir:

PRELIMINARY AMENDMENT

Prior to examining the above-referenced application, the Applicants request the  
application be amended as follows.

IN THE SPECIFICATION

Please replace the paragraph [0001] with the following paragraph:

**[0001]** This application is a continuation-in-part of co-pending United States  
Patent Application No. 09/505,899 (AMAT/4100), filed on February 17, 2000, <sup>and</sup> a  
continuation-in-part of co-pending United States Patent Application No. 10/026,854  
(AMAT/5765), filed on December 20, 2001; and claims benefit of United States  
Provisional Patent Application Serial Number 60/286,107, filed April 24, 2001, (AMAT  
5844L) and United States Provisional Patent Application Serial Number 60/326,263,